

assembling and dispensing of complex micro systems

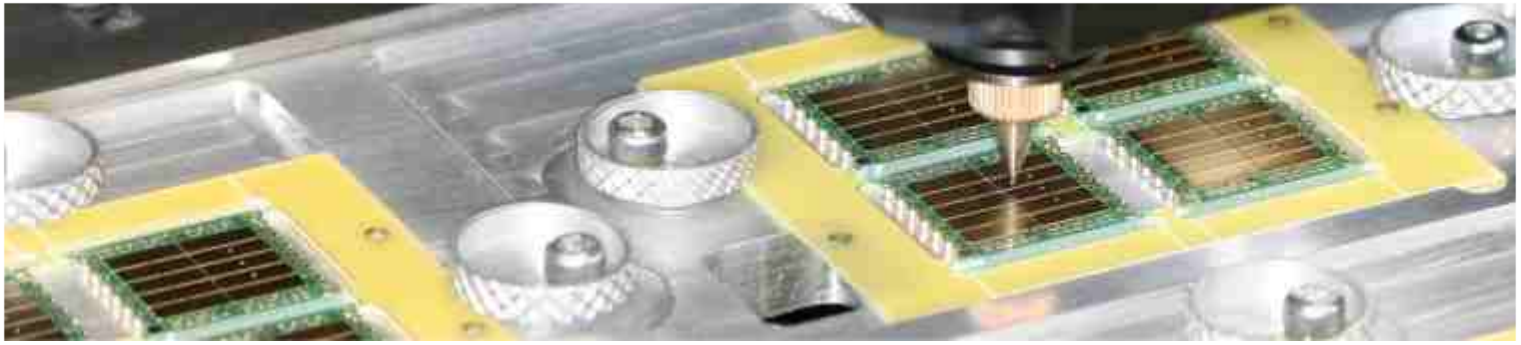
Multi Chip on Board – inductive and capacitive micro sensors
Flip Chip on Glass – optical length measuring systems
Chip on Flex – weather sensors
3D Multi Chip on MID – sun sensors
Multi Chip & SMD on Ceramic – micro wave applications
MEMS assembly – optical micro sensors

- Die Bonder, Dispenser & AOI on one platform
- Positioning accuracy $\pm 10 \mu\text{m}$ @ 3 sigma
- 3D micro assembly tilt angle $> 90^\circ$
- Dispensing dot $\pm 0,1 \text{ nl}$ @ 6 sigma
- Volume dispensing and 3D dispensing path $\pm 0,01 \mu\text{l}$ @ 6 sigma
- Setup time $< 5 \text{ min}$
- Machine capability $C_{mk} > 2,0$
- Availability $> 97\%$



MicroWorld

VICO 520 M - Multi Chip & 3D Micro Assembly Equipment



movement system	precision portal with AC-servo drive and optical linear measurement systems
working area (X,Y,Z)	450 x 480 x 40 mm (depending on configuration)
repeating precision	0.001 mm
placing head	placing head with rotation axis, vacuum tool, changeable force decoupled tools
tool rotation	>360°
axis resolution	±0.008°
touchdown force	analogously adjustable from 0.2 to 60 N
dispenser	one or two dispense heads with automatic volume controlled dosing and filling control
dispense accuracy	±0.01 nl
material storage	3 to 30 ml disposable cartridge
range of viscosity	0.5 to 500.000 mPa·s
dosing force	max. 240 N
vision system	3D-recognition with integrated height measurement
search area (X,Y,Z)	±2.0 mm
rotation area	±180°
measurement resolutions (X,Y,Z)	±0.002 mm
optical controlling	integrated 3D AOI functions for pre- and postinspection
supply of components	standard and special supply of components installable in the whole working area
SMD tape feeder	supply from 4 sides
SMD stick feeder	max. 75 x SMD tapes 8 to 44 mm
waffle pack holders	max. 75 x SMD sticks 6 to 22 mm
gel-pak holders	twofold to eightfold waffle-tray 2 to 4 inch
die eject	station with vacuum-control for gel-pak 2 to 4 inch
wafer changer	single wafer or double wafer units for 2 to 8 inch wafer
	tenfold and twentyfold wafer changer
additional equipment	universal, vacuum and heating substrate support
	3D substrate support with two additional axes
	SMEMA transport system with automatic width adjustment
	standard and fine force tool intakes
	automatic tool changer with tool detection
	sub side recognition camera ±0.002 mm
	3D horizontal recognition camera ±0.001 mm
	part inspector for part recognition ±0.002 mm
	flip station with automatic adjustment for different component heights
	direct dispense station for glueing, pin transfer and fluxing
	optical 3D measurement of the needle ±0.005 µm
	automatic cleaning of the dispense needle
	controlled needle heating
	process observation camera for monitoring
	integrated precision scale for weight control and process release
	network and main computer connection
	multilingual software under windows
machine specifications	CE-conform
weight	850 to 1000 kg
size (w,d,h)	1450 x 1450 x 1850 mm
power supply	400 V 3LNPE, 50/60 Hz, 3.500 VA
compressed air	≥5 bar, 60 l/min, clean, dry, oil free
operation and environment conditions	floor carrying capacity > 500 kg/m²
	floor should be stable and free from vibrations
	room temperature 20 to 24° C
	relative humidity < 60%, constant light conditions